REMARKS

Applicants request favorable consideration and allowance of the subject application in view of the preceding amendments and the following remarks

To place the application in better form, the specification has been amended to note its continuing status and to correct minor informalities. Also, a new abstract is presented in accordance with preferred practice. No new matter has been added by these changes.

Claims 14-22 are presented for consideration in lieu of claims 1-13, which have been canceled without prejudice or disclaimer. Claims 14, 15, 17, 18, 20 and 21 are independent. Support for these claims can be found in the original application, as filed. Therefore, no new matter has been added.

Applicants submit that claims 14-22 patentably define features of the load-lock chamber, the substrate processing system, the exposure processing system, and the device manufacturing method of the present invention. Applicants submit, therefore, that the instant application is in condition for allowance. Favorable reconsideration and an early Notice of Allowance are requested.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address listed below.

Respectfully submitted,

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